

SUBSTRATE DESCRIPTION APPARATUS

ABSTRACT

Provided is a substrate processing apparatus for processing a substrate, the substrate processing apparatus having: composite modules in each of which one transfer chamber having a transfer space for the substrate and a processing chamber having a processing space for the substrate are integrated, in which the composite modules are connected by connecting the transfer chambers adjacent to each other. The transfer spaces of the transfer chambers connected to each other communicate with each other. The transfer space is maintained in a vacuum atmosphere.

Figure 7